



MOCVD LAB IN ENGINEERING CENTERS BUILDING

16C1Y



Summary – This project remodels suite 206d in the Engineering Centers Building for a new facility recruit involved in Metal Organic Chemical Vapor Deposition (MOCVD) used in the manufacturing of computer chips. It will be an H5 hazardous occupancy with intensive equipment needs.

▼ BUDGET

TOTAL \$ 756,000

FUNDING SOURCES

Gifts & Grants \$ 756,000

ESTIMATED BUDGET BREAKDOWN

Construction \$ 608,000

Design \$ 60,800

DFD Mgt. \$ 27,000

Contingency \$ 60,800

Equipment \$ 0

Other Fees \$ 0

Construction \$/GSF \$ N/A

Total Project \$/GSF \$ N/A

▼ TIMELINE

A/E Selection 04/2016

Planning N/A

Programming N/A

10% Concept Report N/A

35% Design Report 05/2016 – 07/2016

Construction Documents 07/2016 – 08/2016

Bid Date 12/2016

Construction **02/2017 – 06/2017**

Substantial Completion 07/2017

Occupancy 07/2017

▼ AREA DATA

GSF N/A

ASF 1,320

Efficiency N/A

▼ ISSUES

There are currently issues for this project in the following areas:

- **Cost**
- **Schedule conflicts**

▼ KEY STAKEHOLDERS

Occupants College of Engineering
User Reps Sharon Devenish

UW PM Pete Heaslett
DFD PM Doug Schorr

A/E KEE Architects
Design Arch. N/A
Landscape Arch. N/A
Structural Engr. N/A

Delivery Method Single Prime
General N/A
Plumbing N/A
Mechanical N/A
Fire Protection N/A
Electrical N/A